

Notice of References Cited	Application/Control No. 09/660,317	Applicant(s)/Patent Under Reexamination CAMRAS ET AL.	
	Examiner Monica Lewis	Art Unit 2822	Page 1 of 1

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	C	US-5,553,089	09-1996	Seki et al.	372/43
	D	US-2002/0030194	03-2002	Camras et al.	257/98
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NON-PATENT DOCUMENTS

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	V	Thomas R. Anthony, Dielectric Isolation of Silicon by Anodic Bonding, 1985, pages 1240-1247.
	W	Cerac Technical Publication, Aluminum Oxide
	X	J.W. Osenbach et al., Low Cost/High Volume Laser Modules Using Silicon Optical Technology, IEEE Electronic Components and Technology Conference, 1998.

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.